

NARROW GAP ELECTRONEGATIVE CAPACITIVE DISCHARGES AND STOCHASTIC HEATING

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Motivation: widely used for thin film etch and deposition

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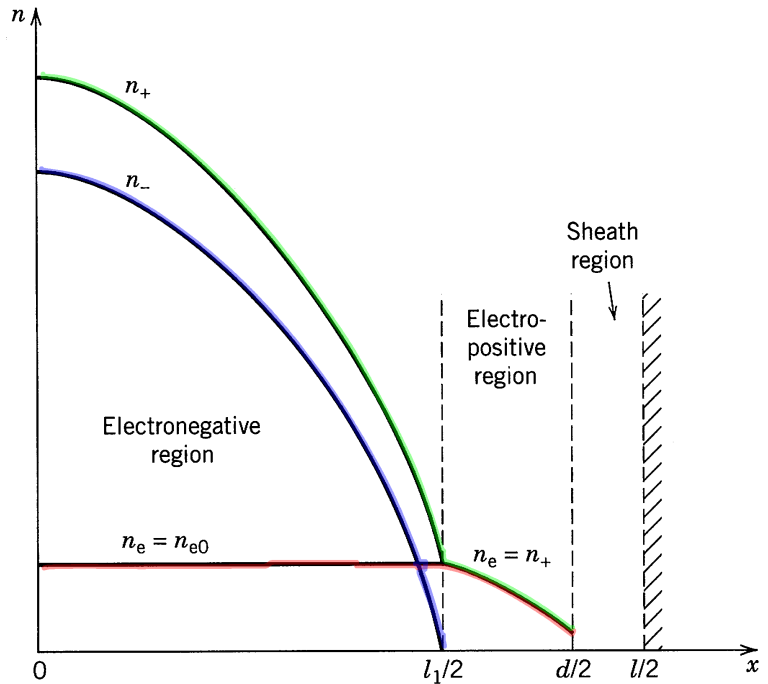
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OUTLINE

- PIC simulations of narrow gap oxygen discharges
- Equilibrium discharge model
- Stochastic (collisionless) heating

DISCHARGE CONFIGURATION

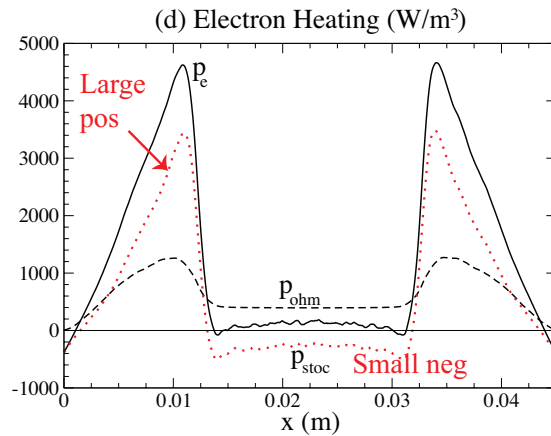
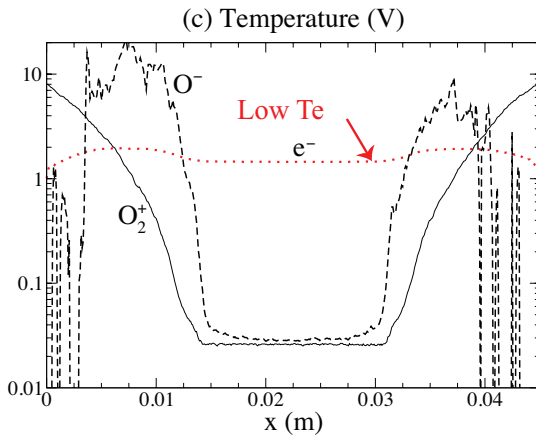
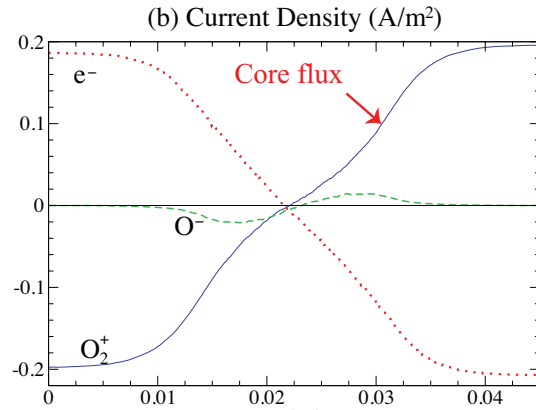
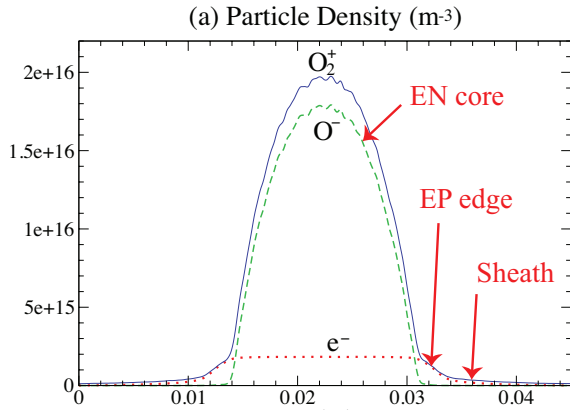
- Oxygen at 10–100 mTorr, $V_{\text{rf}} = 500\text{--}2000\text{ V}$
- 1D plane-parallel geometry ($\sim 1\text{--}10\text{ cm}$ gap length L)
- Usual model is stratified discharge with electronegative (EN) core and electropositive (EP) edge



- As L is decreased, the EP edge can disappear and new interesting phenomena are found

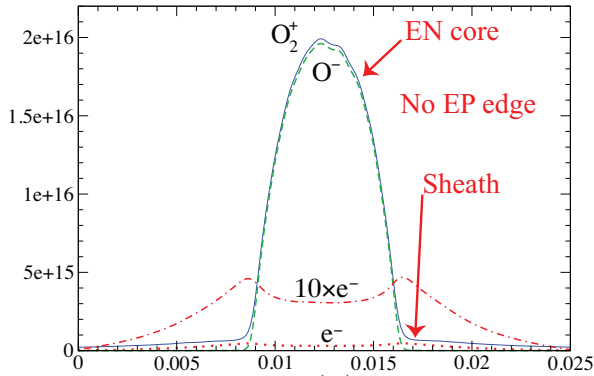
PIC SIMULATIONS AND EQUILIBRIUM MODELING
(Vary gap length L at $p=50$ mTorr, $V_{\text{rf}} = 500$ V)

L=4.5 cm (EP EDGE EXISTS)

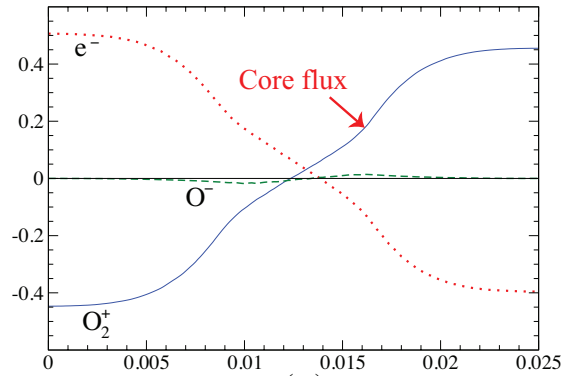


L=2.5 cm (NO EP EDGE)

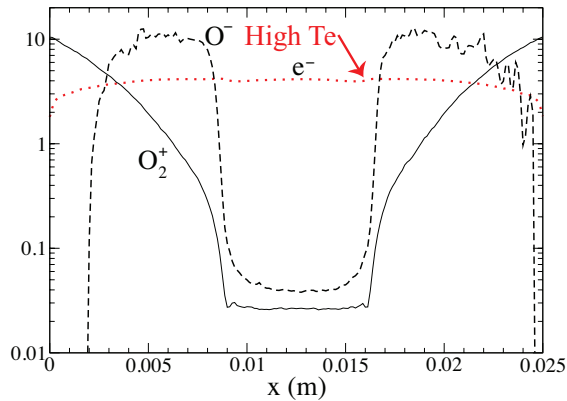
(a) Particle Density (m^{-3})



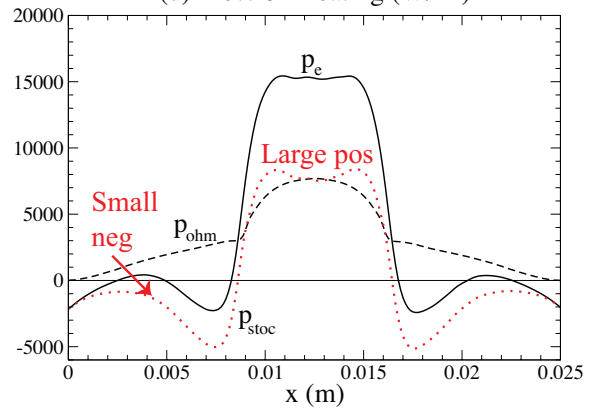
(b) Current Density (A/m^2)



(c) Temperature (V)

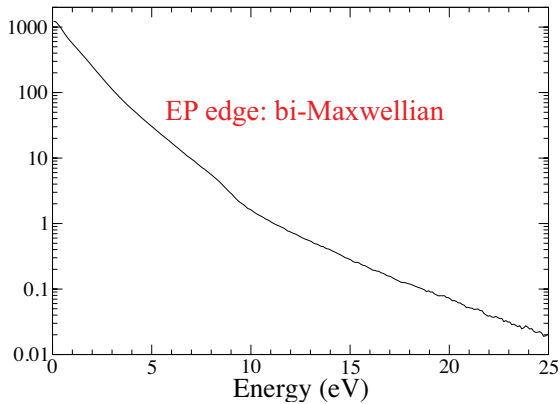


(d) Electron Heating (W/m^3)

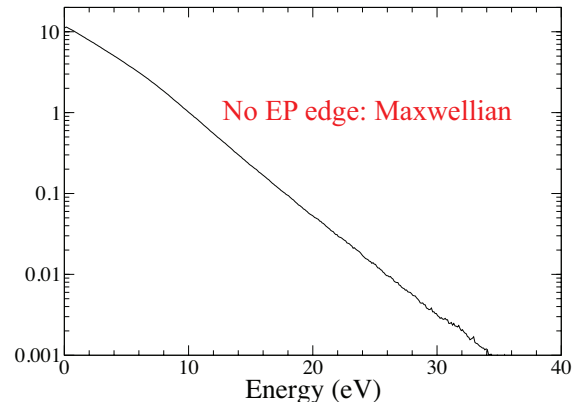


EEDF'S AND DENSITY DETAILS

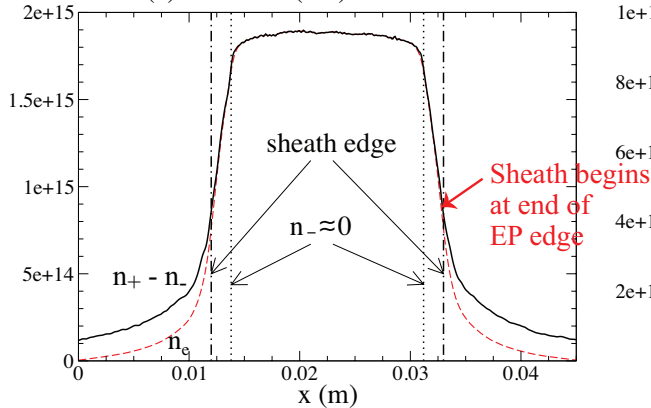
(a) EEDF (a.u.) for $L = 4.5$ cm



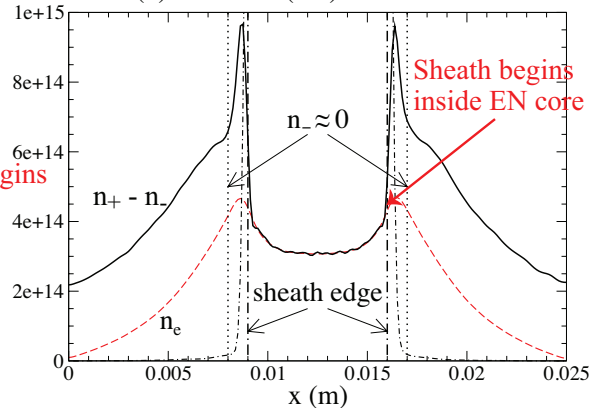
(b) EEDF (a.u.) for $L = 2.5$ cm



(a) Densities (m^{-3}) for $L = 4.5$ cm

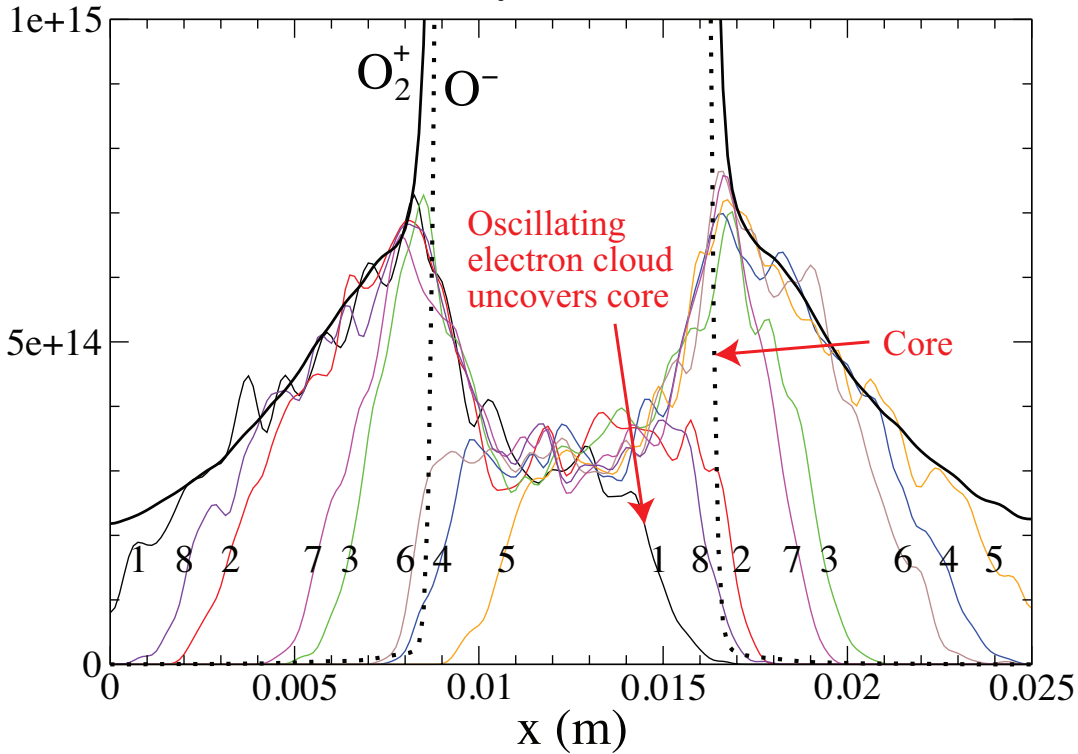


(b) Densities (m^{-3}) for $L = 2.5$ cm



TIME-VARYING DENSITY (L=2.5 cm, NO EP EDGE)

Electron density (m^{-3}) at T/8 intervals

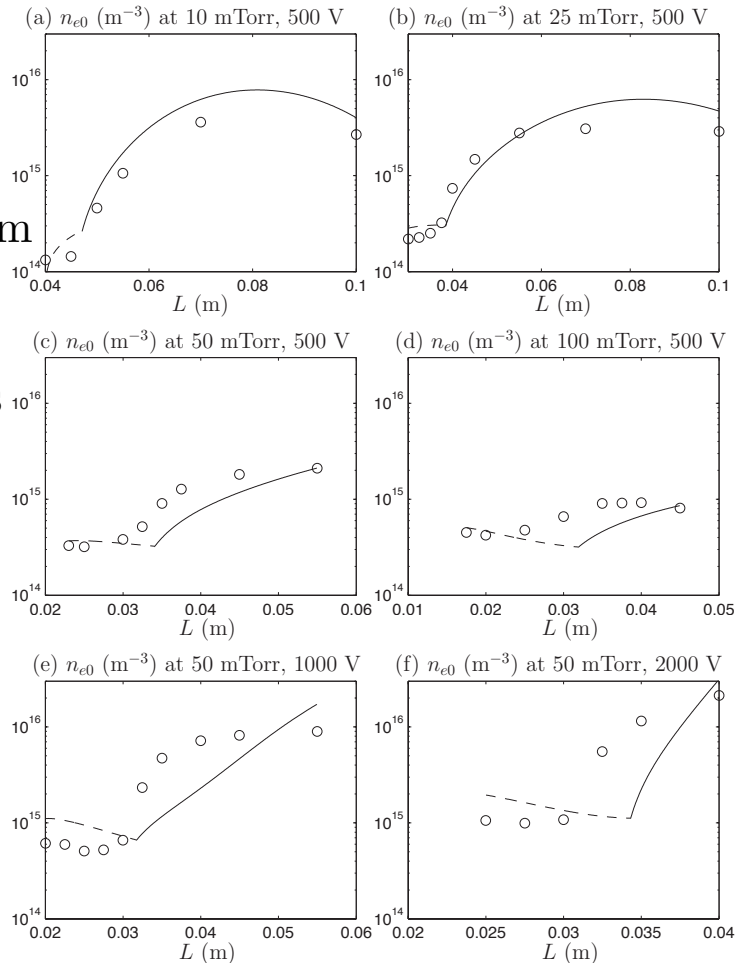


MODELING CONSIDERATIONS

- EP edge exists (larger gap lengths L)
 - Bi-Maxwellian EEDF
 - About half the ion flux generated in sheath/EP edge
 - Usual Child law rf sheath
 - Usual positive collisionless heating in sheath
- No EP edge (smaller gap lengths L)
 - Maxwellian EEDF
 - Over half the ion flux generated in sheath
 - Attachment in sheath is important
 - Unusual rf sheath containing negative ions
 - Negative collisionless heating in sheath, positive in core
- Models developed:
 - model with some inputs from PIC results
 - self-consistent model

MODEL WITH SOME INPUTS FROM PIC

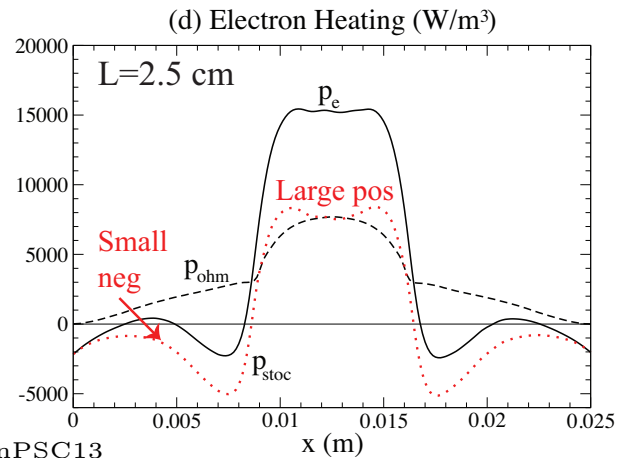
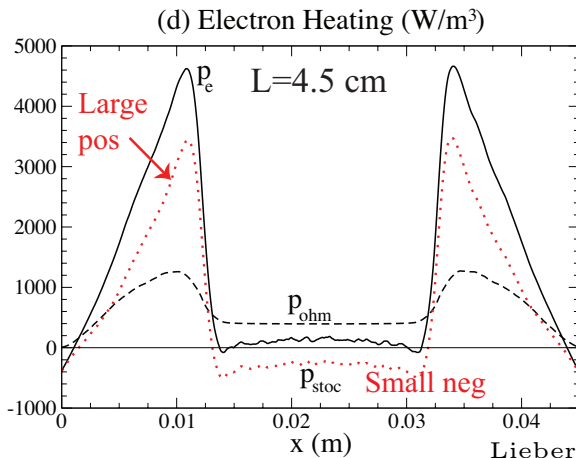
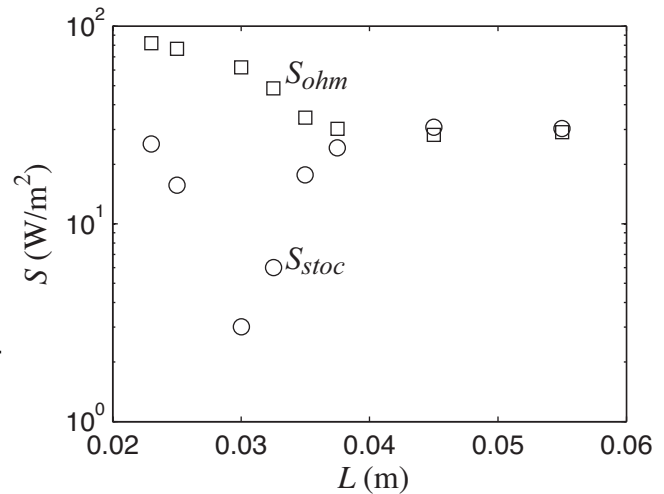
- Rate coefficients and collisional energy losses using PIC EEDF
- Power deposition in core from PIC results
- Solid lines (2-region model with EP edge); Dashed lines (1-region model without EP edge); circles (PIC results)
- Reasonable agreement between model and PIC results (submitted to Physics of Plasmas, 2013)



STOCHASTIC (COLLISIONLESS) HEATING

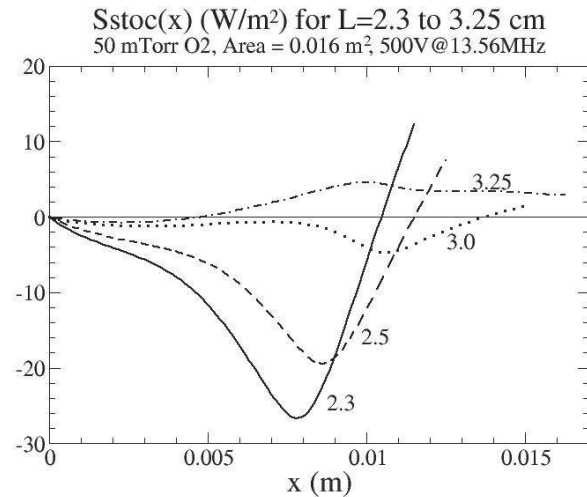
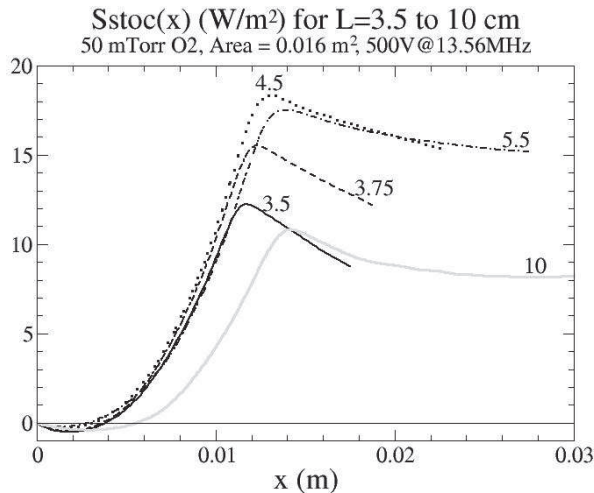
PIC RESULTS FOR VARIOUS GAPS L (50 mT, 500 V)

- Stochastic heating small at transition where EP edge disappears
- EP edge exists \Rightarrow positive heating in sheath, negative in core
- No EP edge \Rightarrow negative heating in sheath, positive in core



INTEGRATED $S_{\text{stoc}}(x)$ FOR VARIOUS GAPS L

- Integrate power density $p_{\text{stoc}}(x)$ from electrode toward discharge midplane



- Large $L \Rightarrow n_e(\text{core}) > n_e(\text{sheath})$
 \Rightarrow positive heating in sheath, negative heating in core
- Small $L \Rightarrow n_e(\text{sheath}) > n_e(\text{core})$
 \Rightarrow negative heating in sheath, positive heating in core

TWO-STEP DENSITY MODEL

1. I.D. Kaganovich, Phys. Rev. Lett. **89**, 265006 (2002).
2. E. Kawamura, M.A. Lieberman and A.J. Lichtenberg, Phys. Plasmas **13**, 053506 (2006).

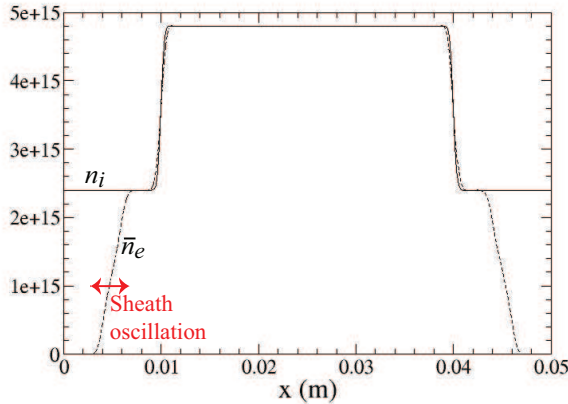
Use to investigate stochastic heating

FIXED IONS, PIC ELECTRONS (30 mT Ar, 13.56 MHz)

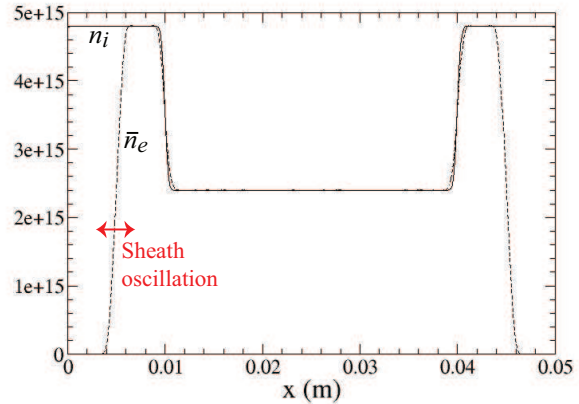
(Models EN plasma with EP edge)

(Models EN plasma with no EP edge)

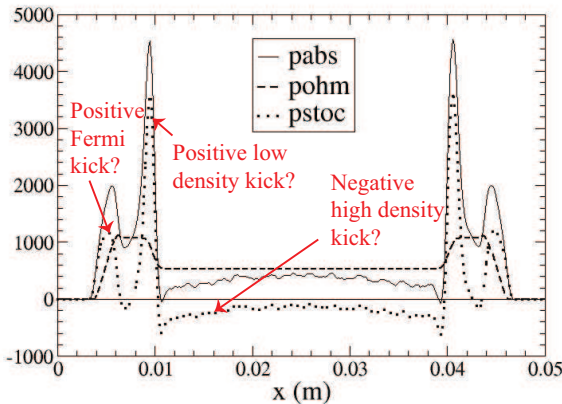
Plasma Density (m^{-3})



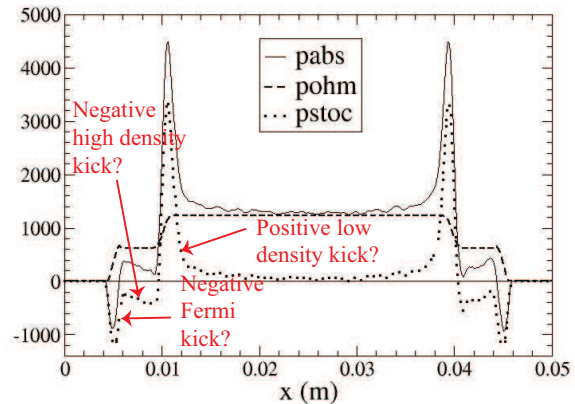
Plasma Density (m^{-3})



Electron Heating (W/m^3)



Electron Heating (W/m^3)



SUMMARY

- A transition from an EN discharge with an EP edge, to a narrower gap discharge with no EP edge, was investigated with PIC simulations and modeling
- The effects of a bi-Maxwellian EEDF, with an EP edge, and sheath attachment and core uncovering, with no EP edge, need to be taken into account in modeling
- A transition from sheath to internal stochastic heating after the EP edge disappears is observed, and is being studied with a fixed ion, two-step density, PIC simulation